

2009 spring

Microstructural Characterization of Materials

04. 22. 2009

Eun Soo Park

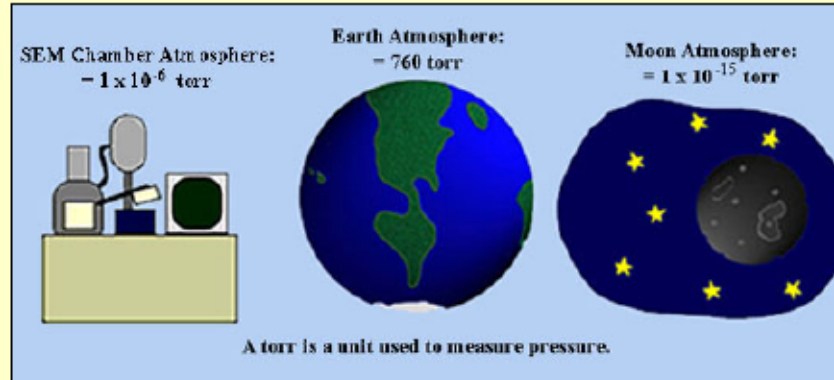
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Office hours: by an appointment

Vacuum



When a SEM is used, the column must always be at a vacuum. There are many reasons for this. If the sample is in a gas filled environment, an electron beam cannot be generated or maintained because of a high instability in the beam. Gases could react with the electron source, causing it to burn out, or cause electrons in the beam to ionize, which produces random discharges and leads to instability in the beam. The transmission of the beam through the electron optic column would also be hindered by the presence of other molecules. Those other molecules, which could come from the sample or the microscope itself, could form compounds and condense on the sample. This would lower the contrast and obscure detail in the image.

A vacuum environment is also necessary in part of the sample preparation. One such example is the sputter coater. If the chamber isn't at vacuum before the sample is coated, gas molecules would get in the way of the argon and gold. This could lead to uneven coating, or no coating at all.

The Sputter Coater

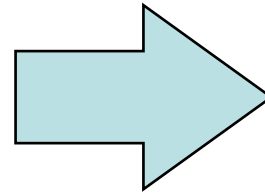


C, Cr, Au-Pd

The sputter coater is used to coat non-metallic samples (bugs, plants, human hair, etc.) with a thin layer of gold. This makes them conductive, and ready to be viewed by the SEM. If the samples are metallic, they can simply be mounted and placed in the SEM

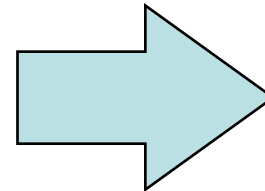
A purpose of coating

1. Give a conduction to specimen surface



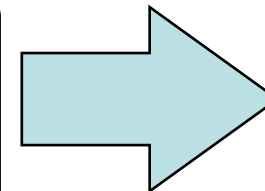
Prevention of charge-up

2. Increase the efficiency of secondary electron



Improvement of Signal to Noise (S/N) ratio

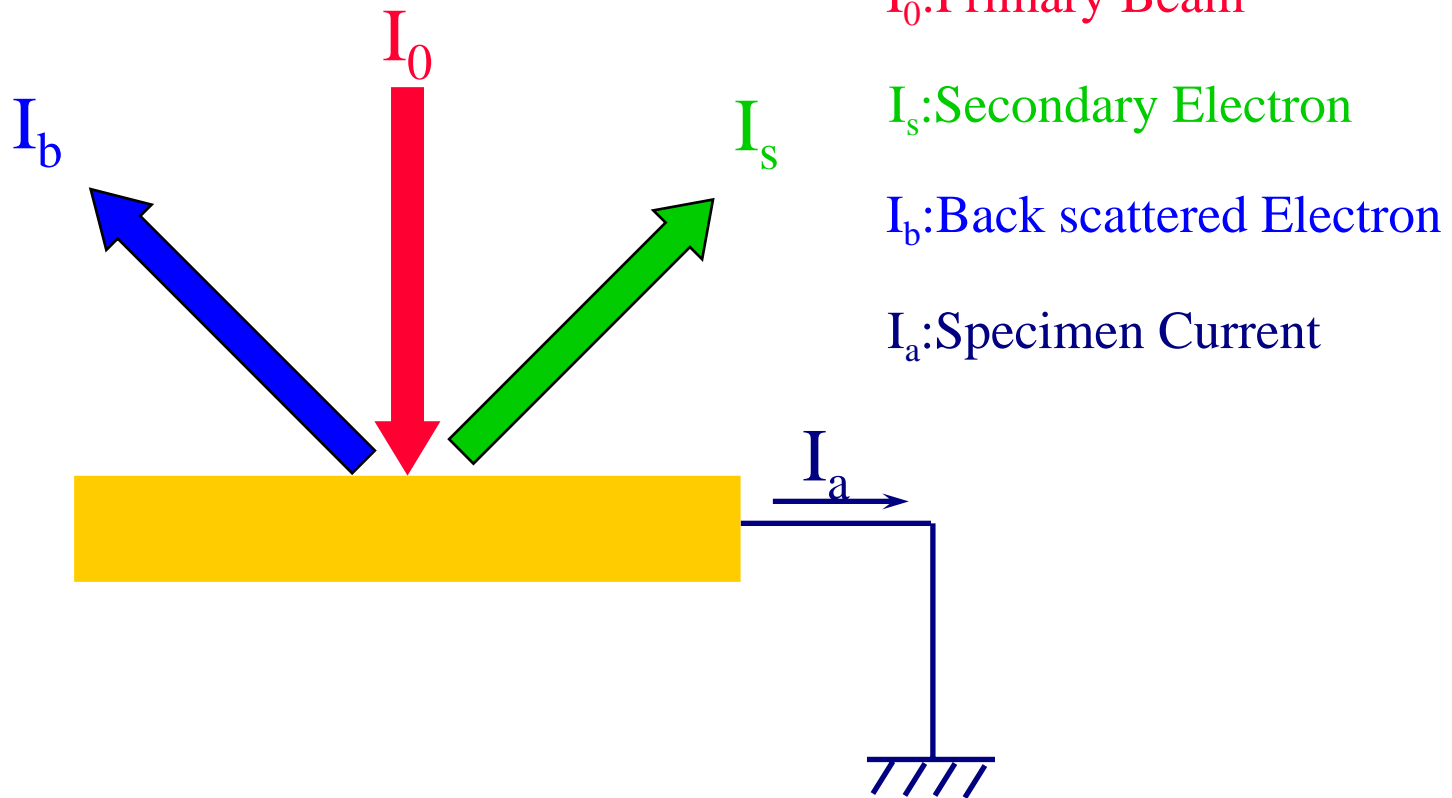
3. Protect the specimen surface against primary electron beam



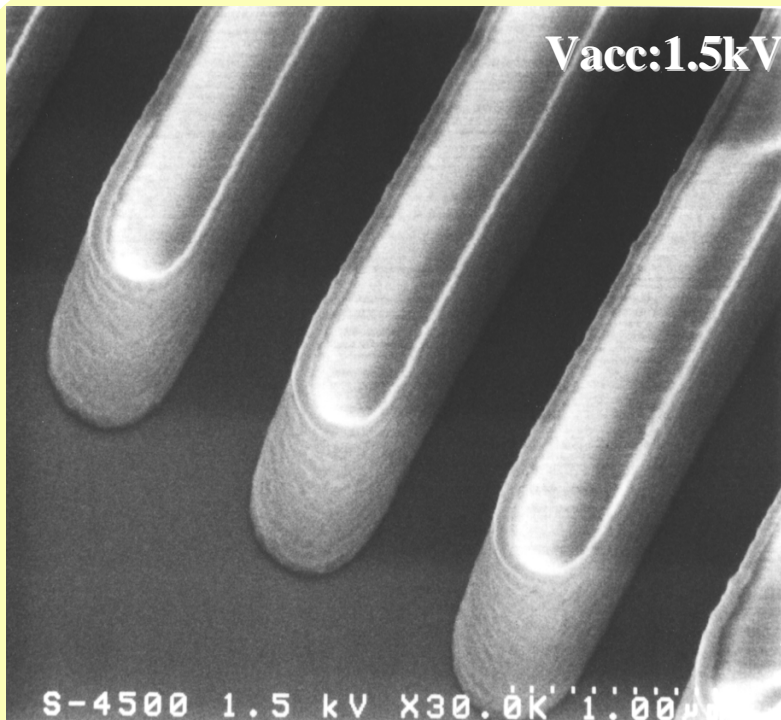
Reduction of damage

Theory of Scanning Electron Microscope

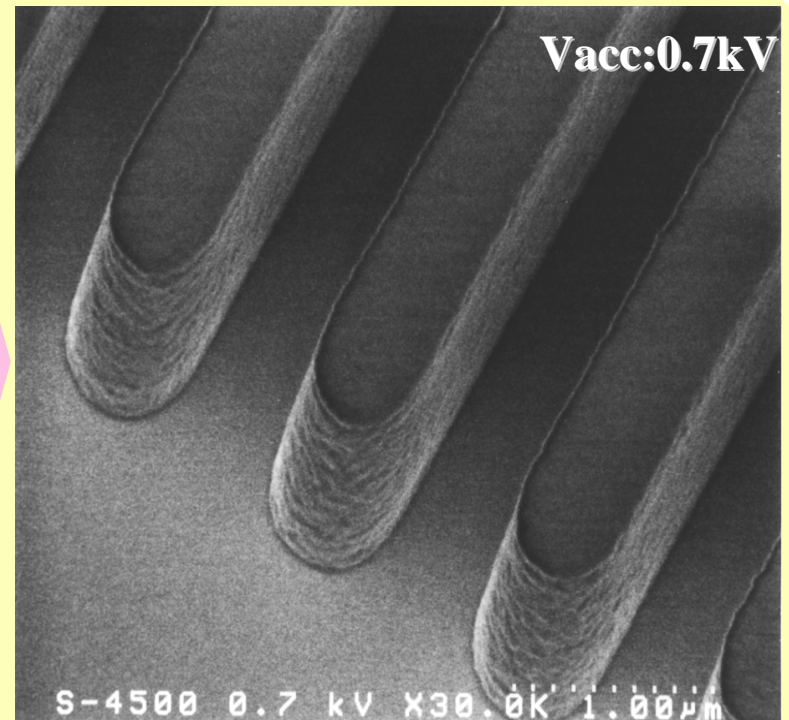
$$\cancel{I_0} = I_s + I_b + I_a \Rightarrow \text{Charge-up}$$



Observation at lower accelerating voltages



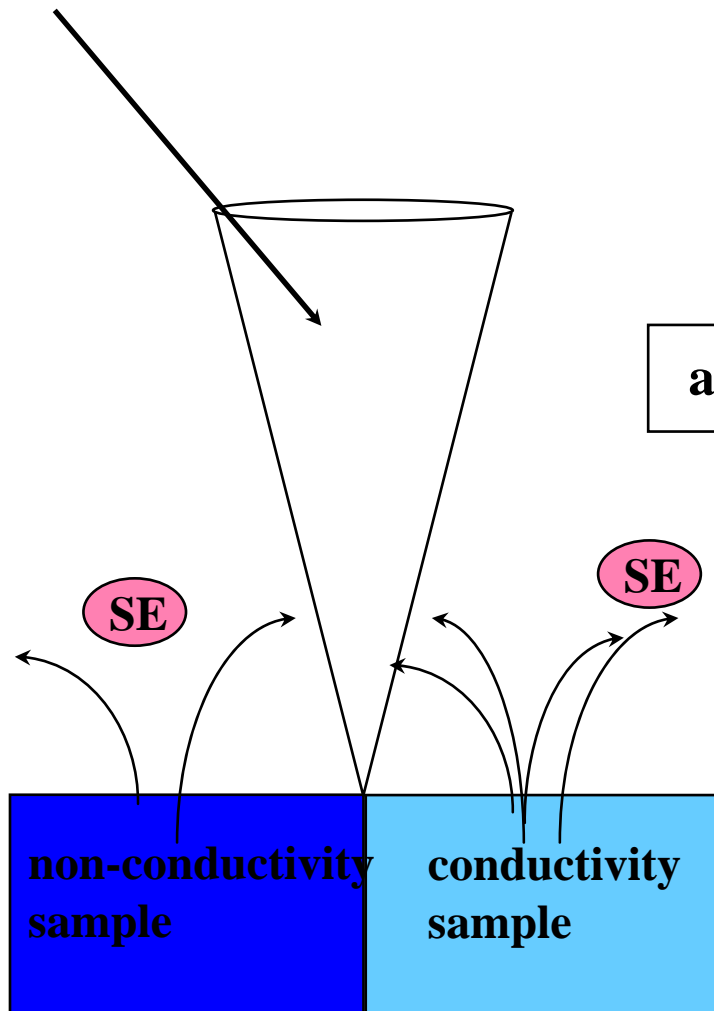
Charge-up Phenomena



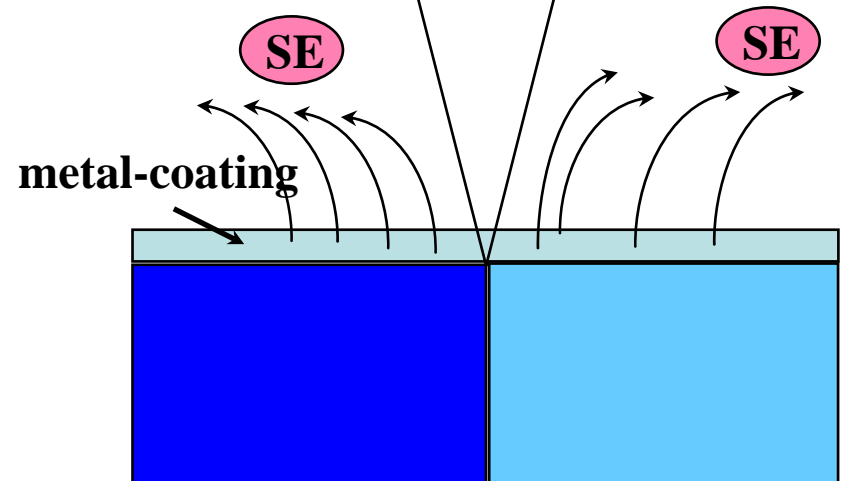
Eliminate Charge-up Phenomena

Specimen : SiO₂ on Photo Resist Line Pattern

primary electron beam

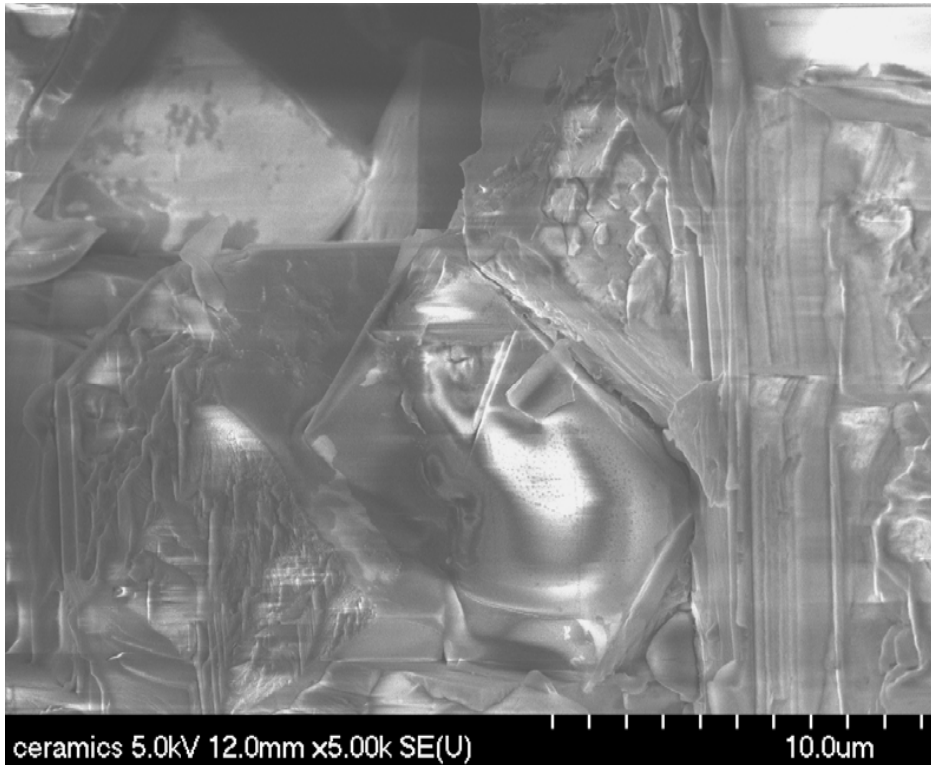


after coating



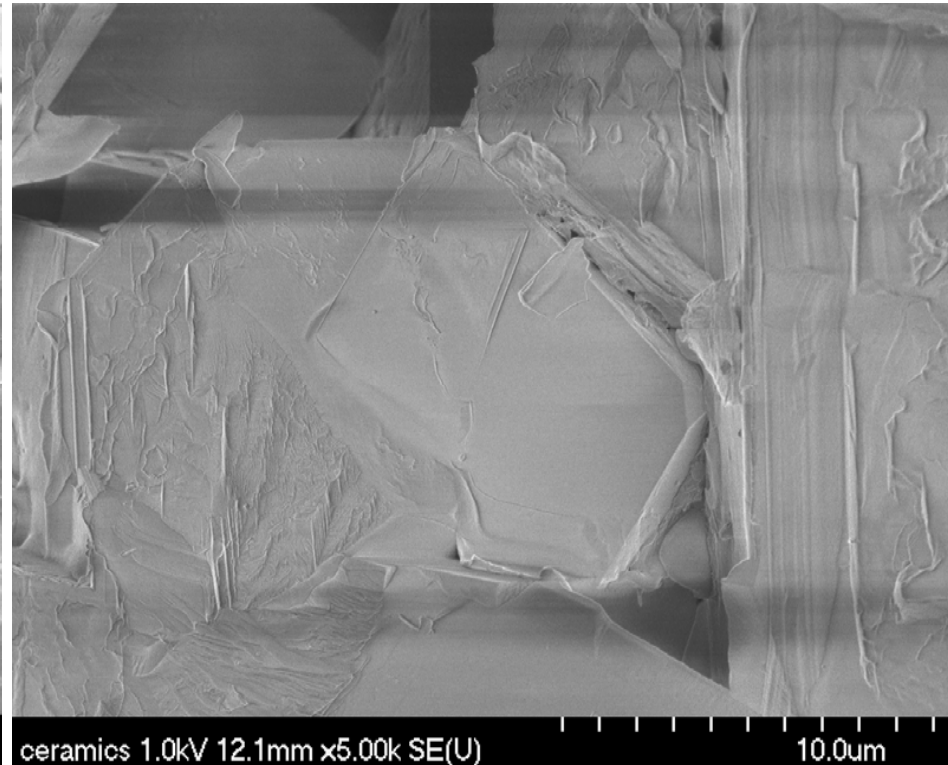
Improvement of (S/N) ratio

Non-Conductive Samples Observation



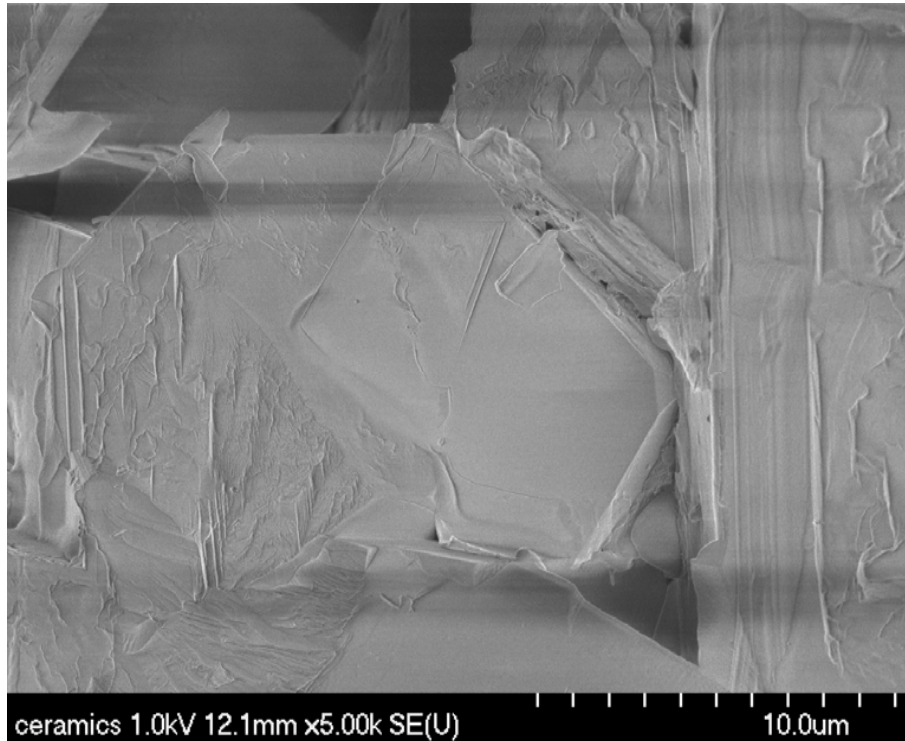
Vacc : 5kV
Upper Detector

Specimen : Ceramics

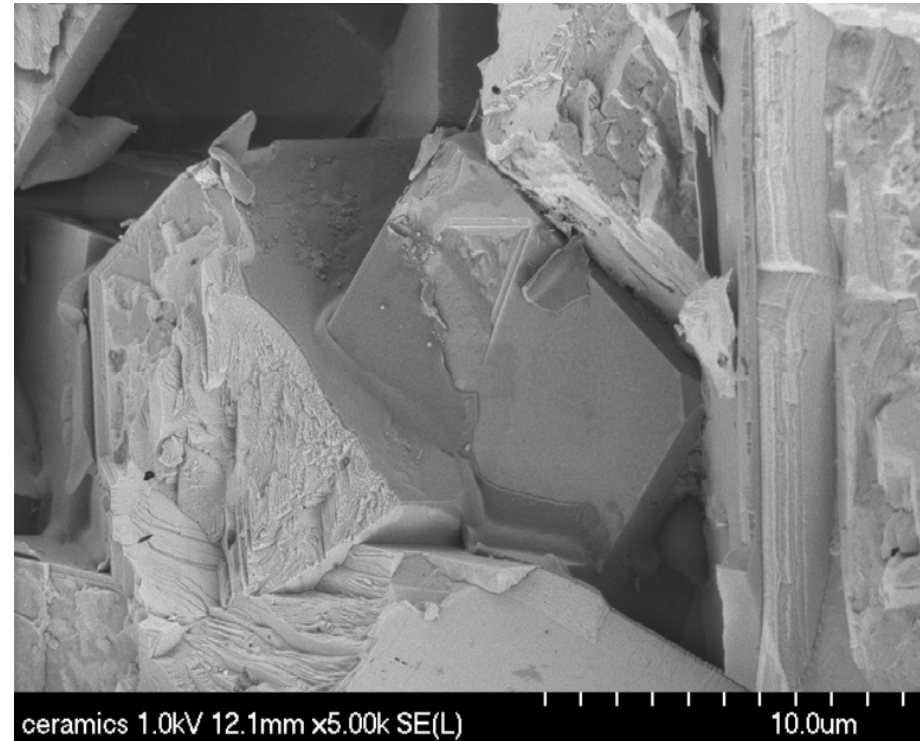


Vacc : 1kV
Upper detector

Non-Conductive Samples Observation



Vacc : 1kV
Upper Detector



Vacc : 1kV
Lower Detector

Specimen : Ceramics

Disturbances

Types of Imaging Disturbances

Image disturbances can be classified by the following expressions:

- **Chromatic aberrations**
- **Images lacking sharpness and contrast**
- **Unstable images**
- **Generally poor-quality images**
- **Noisy images**
- **Images showing jagged edges**
- **Unusual-contrast images**
- **Distorted or deformed images.**

Image Disturbances and Their Causes

(1) Lack of sharpness

- Improper accelerating voltage setting.
- Instability of gun emission caused by insufficient heating of filament.
- Improper electron probe diameter.
- Improper setting and incorrect centering of objective aperture.
- Insufficient astigmatism correction
- Improper focal depth
- Too large magnification
- Specimen charge-up and magnetization
- Defocus of camera system

(2) Low image quality

- Improper accelerating voltage setting
- Improper probe current setting
- Incorrect astigmatism correction
- Noise caused by excessive photomultiplier (PMT) gain
- Improper contrast and brightness
- Improper specimen preparation process
- Improper photographic material
- Improper positional relation between specimen and detector
- No specimen tilting

(3) Noises

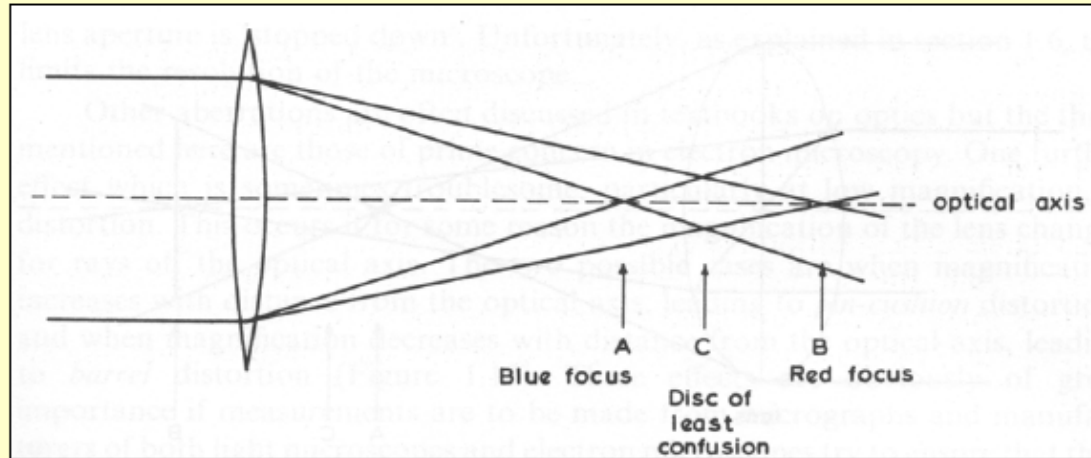
- Instability of accelerating voltage and gun emission
- Discharge of detector
- Charge-up of specimen surface
- Burnt CRT or dusty CRT screen
- External stray magnetic field
- Mechanical vibration

(4) Image distortion and deformation

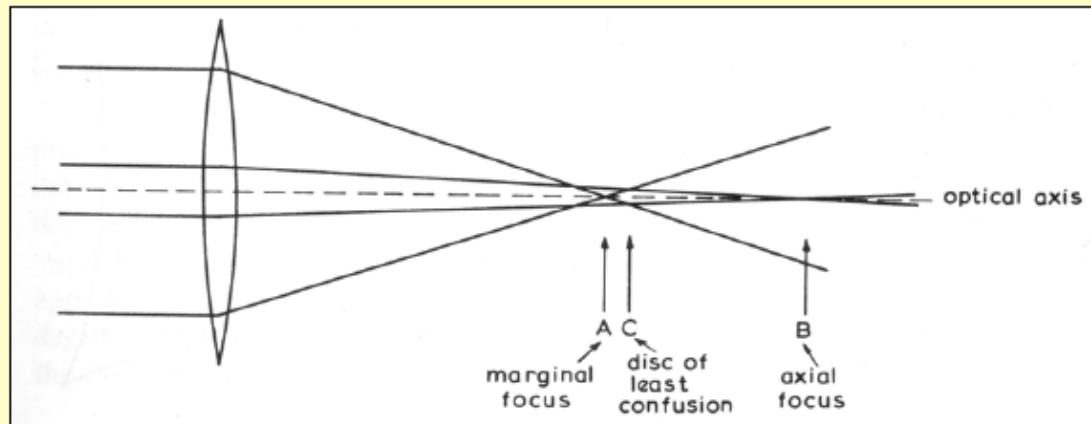
- Specimen charge-up
- External stray magnetic field
- Electron beam damage
- Deformation of specimen itself during its preparation
- Image drift caused by column interior charge-up
- Specimen drift on heating and cooling stages

Aberrations

Chromatic



Spherical



$$r_1 = 0.61\lambda/\alpha \quad r_2 = C_s\alpha^3 \quad \longrightarrow \quad r = r_1 + r_2$$

$$\text{optimized} \longrightarrow \alpha_{\text{opt}} = 0.67\lambda^{1/4}C_s^{-1/4} \quad r_{\text{opt}} = 1.21\lambda^{3/4}C_s^{1/4}$$

Image Changes Caused by Interactions Between Electron Probe and Specimen

Influence of accelerating voltage on image quality:

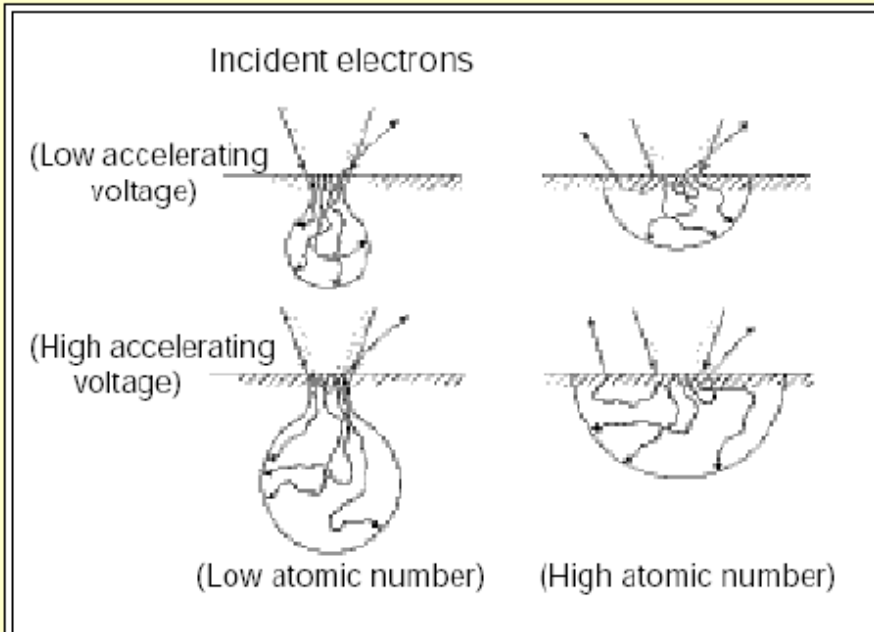


Fig. 1 Diffusion of incident electrons (after Ducumb and Shields).

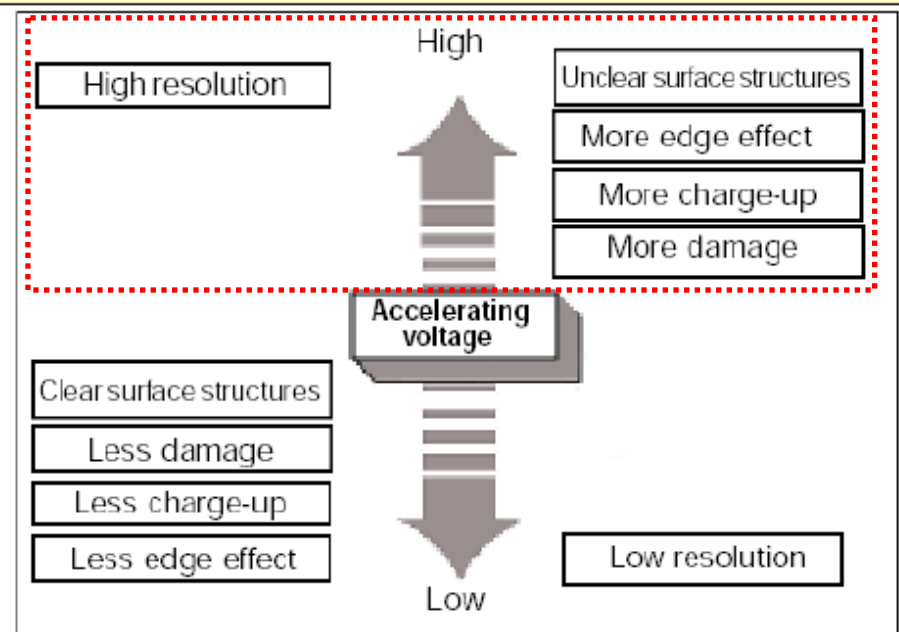
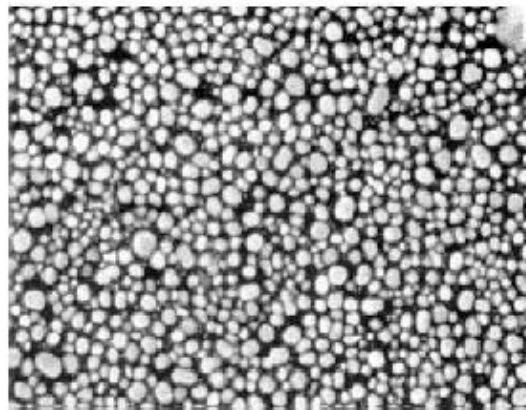


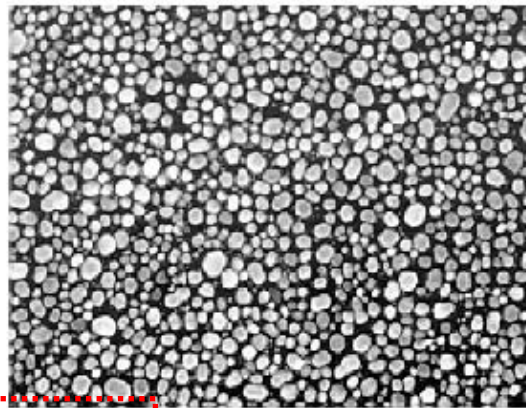
Fig. 2 Effect of accelerating voltage.

Gold particles



(a) 5 kV

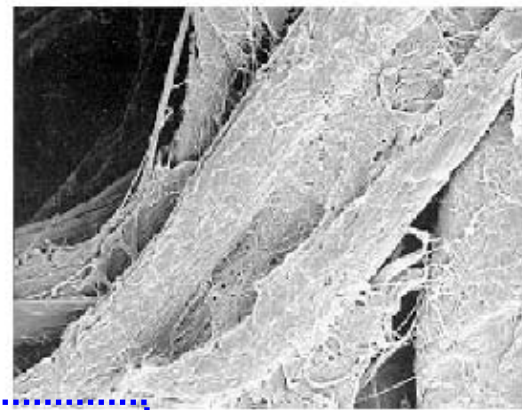
x 36,000



(b) 25 kV

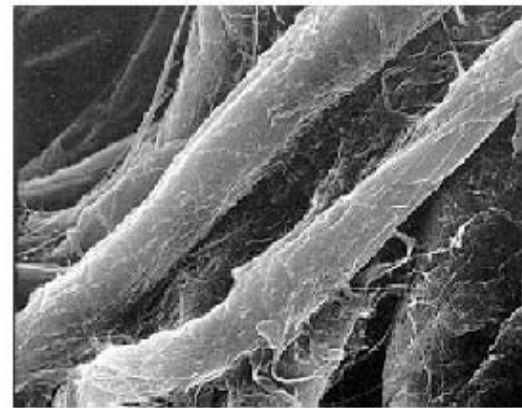
x 36,000

Toilet paper



(a) 5 kV

x 1,400



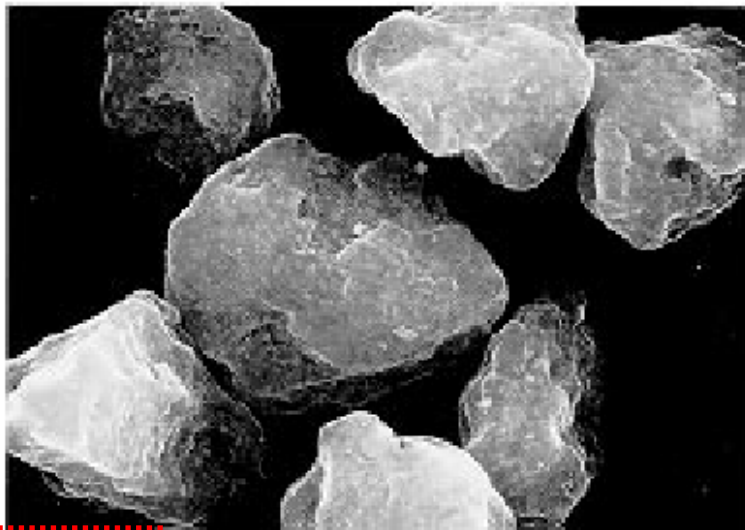
(b) 25 kV

x 1,400

- **LEFT:** The image sharpness and resolution are better at the higher accelerating voltage, 25 kV.
- **RIGHT:** At 5 kV, the microstructures of the specimen surface are clearly seen as the penetration and diffusion area of incident electrons is shallow.

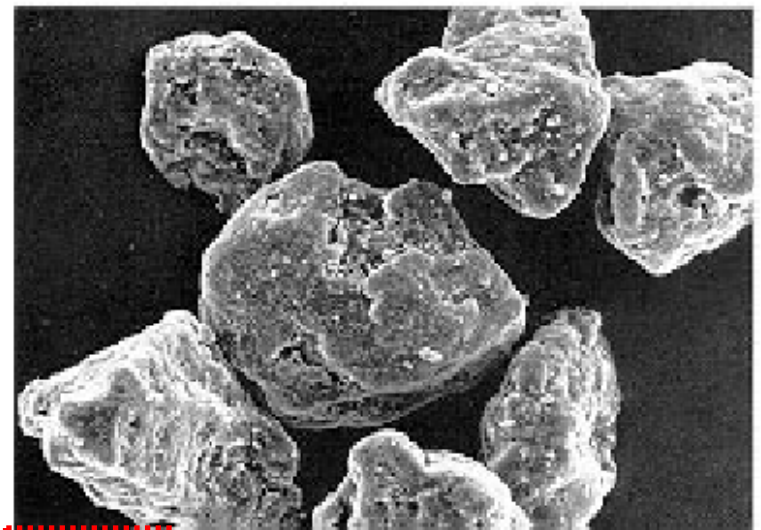
Accelerating Voltage Influence on Image Quality

Toner



(a) 30 kV

x 2,500

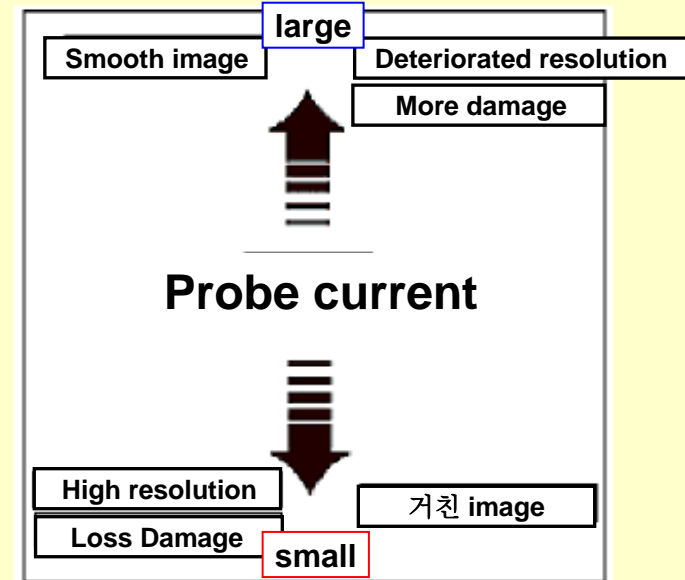
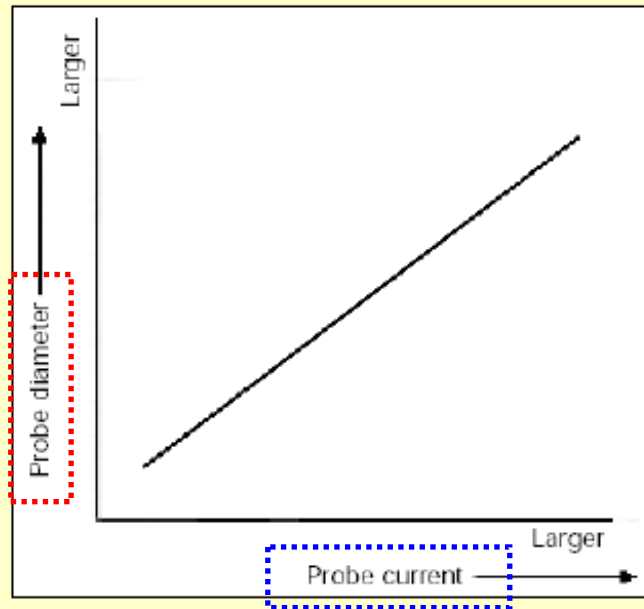


(a) 5 kV

x 2,500

When high accelerating voltage is used as at (a), it is hard to obtain the contrast of the specimen surface structure. Besides, the specimen surface is easily charged up. The surface microstructures are easily seen at (b).

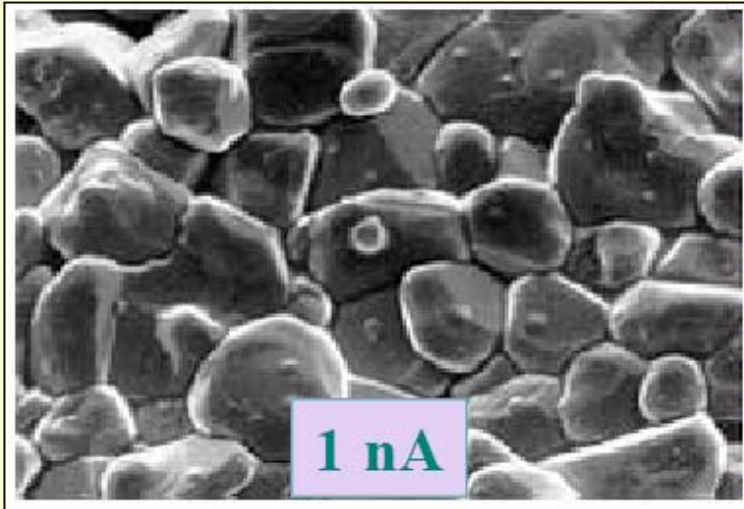
Probe Current, Probe Diameter, and Image Quality



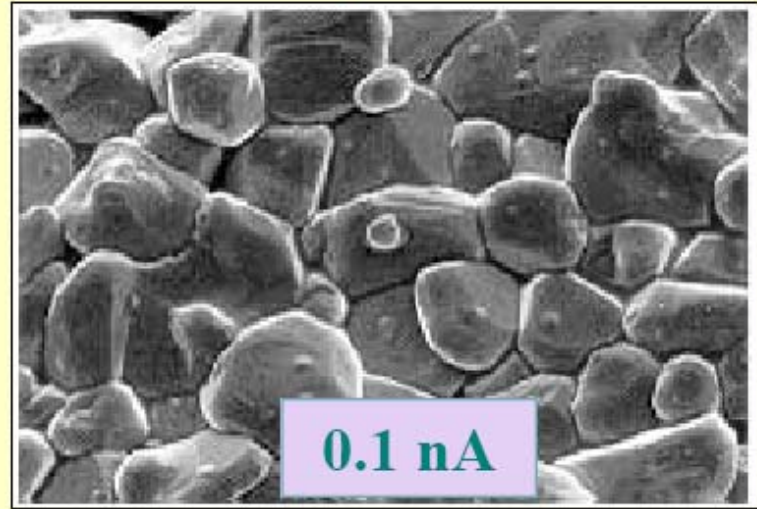
The smaller the electron probe diameter on the specimen, the higher the magnification and resolution. However, the image smoothness, namely, the S/N ratio depends on the probe current. Namely, as the probe diameter is reduced, the probe current is reduced.

It is therefore necessary to select a probe current suited for the magnification and observation conditions (accelerating voltage, specimen tilt, etc.) and the specimen.

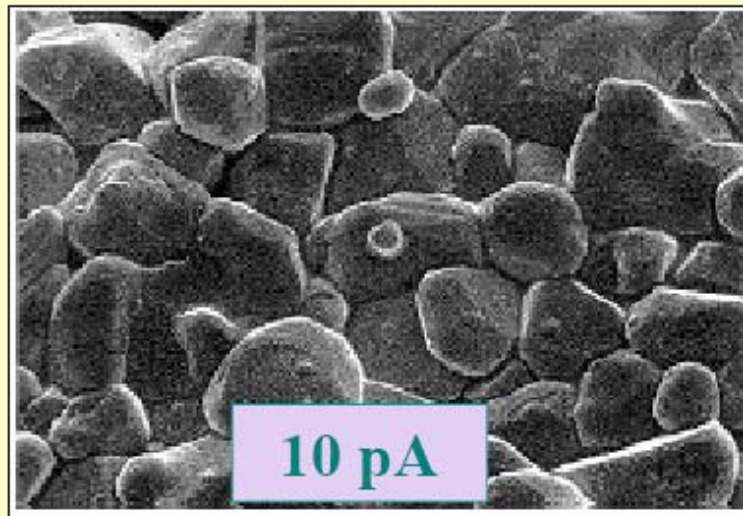
Ceramic, 10 kV, x5,400



$1/10^9$ A



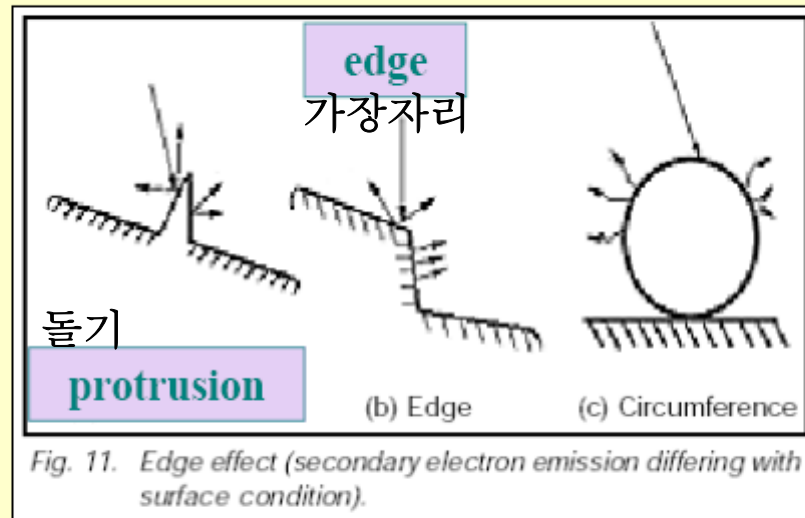
$1/10^{10}$ A



$1/10^{11}$ A

- The smaller the probe current, the sharper is the image, but the surface smoothness is lost.

Edge effect Influence on Image Quality

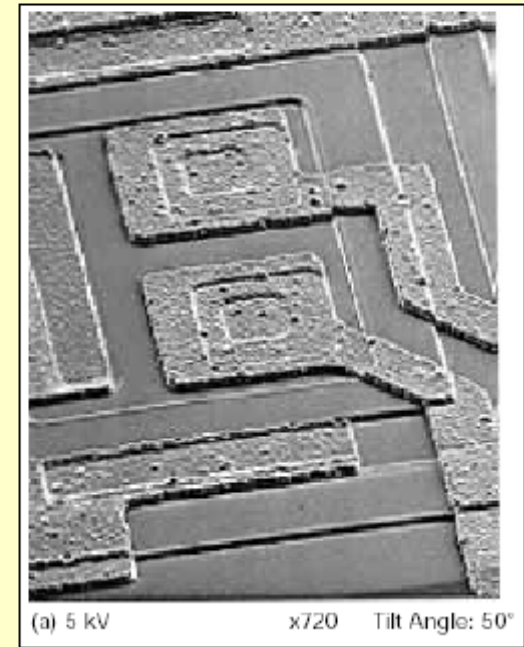
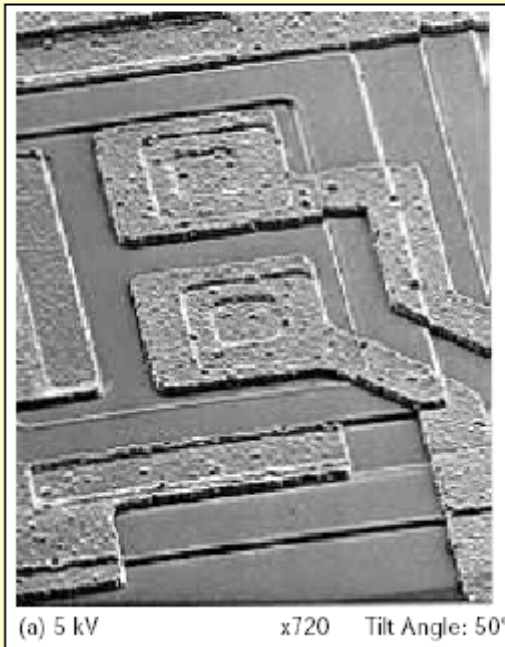


circumference

원주

IC circuit

The higher the accelerating voltage, the greater is the edge effect, making the edges brighter.

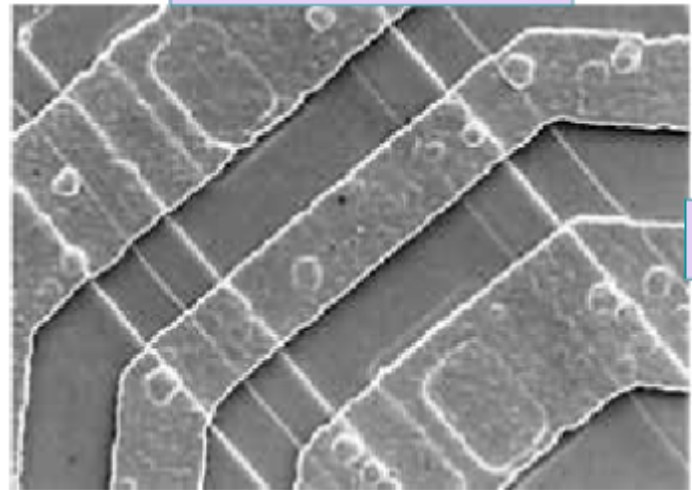


Specimen Tilt

Specimen tilt is aimed at:

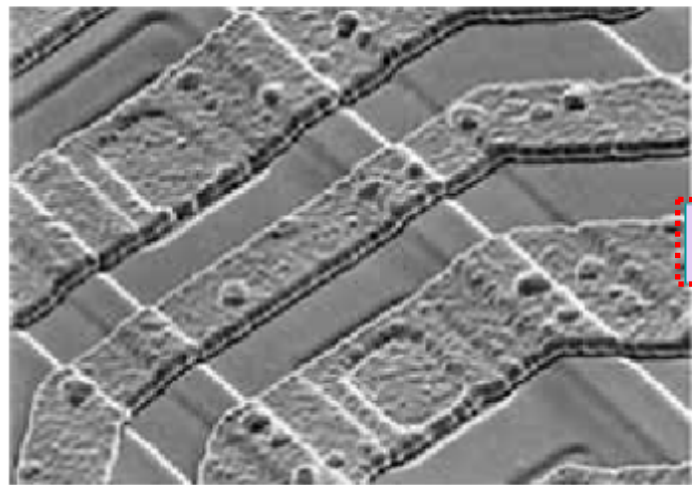
- Improving the quality of secondary electron images
 - Obtaining information different from that obtained when the specimen is not tilted, that is, observing topographic features and observing specimen sides.
 - Obtaining stereo
- micrographs.

IC circuit



(a) Tilt angle: 0°

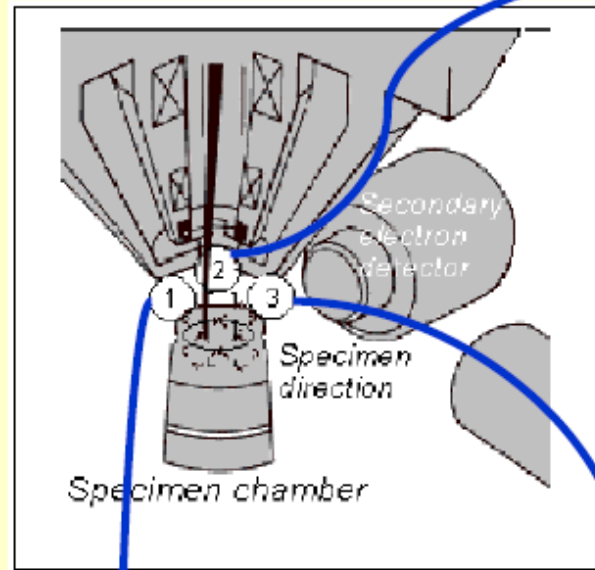
0°



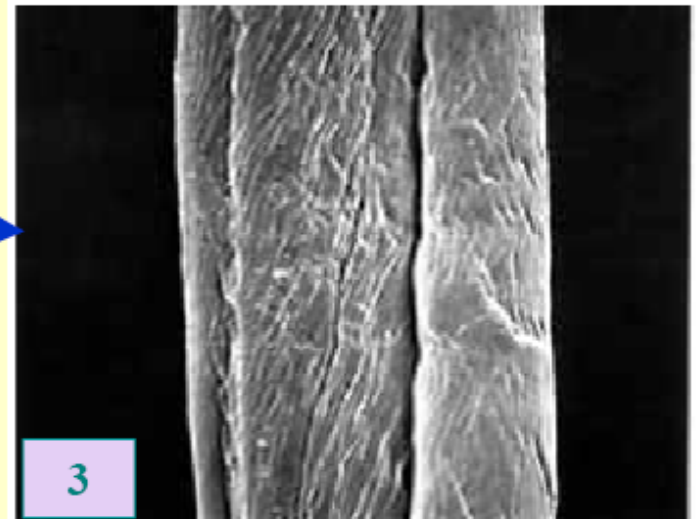
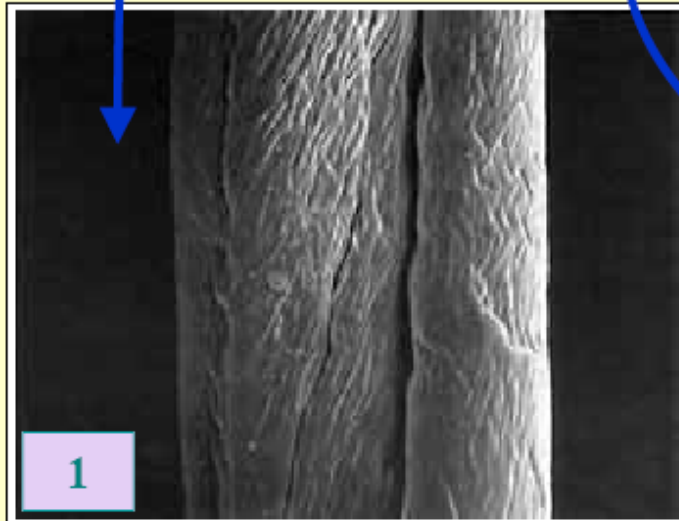
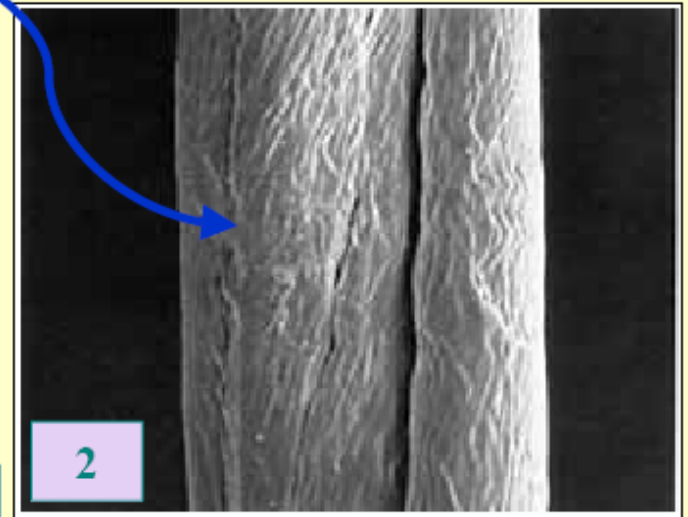
(b) Tilt angle: 45°

45°

Detector position and specimen direction



Fiber



Composition of Signals

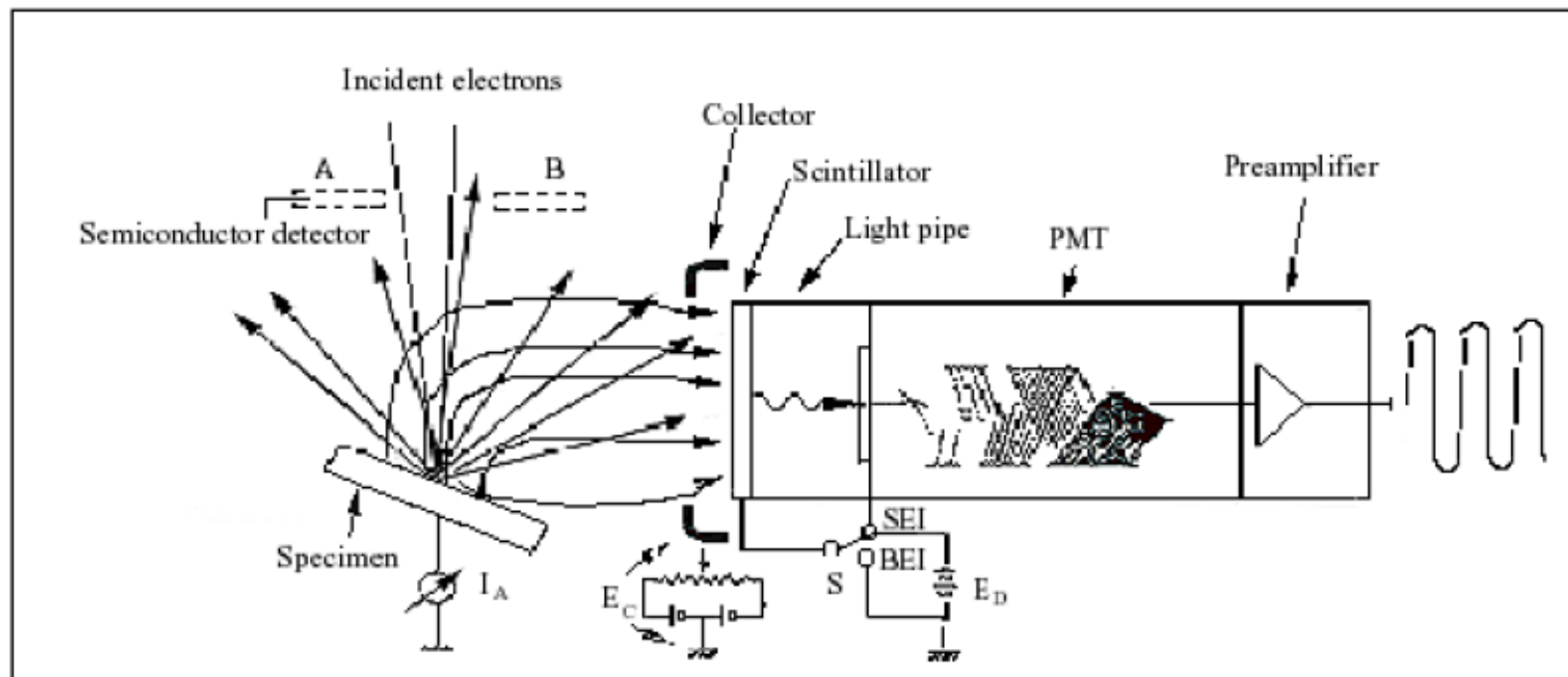


Fig. 17 Secondary electron detector

Composition of Signals

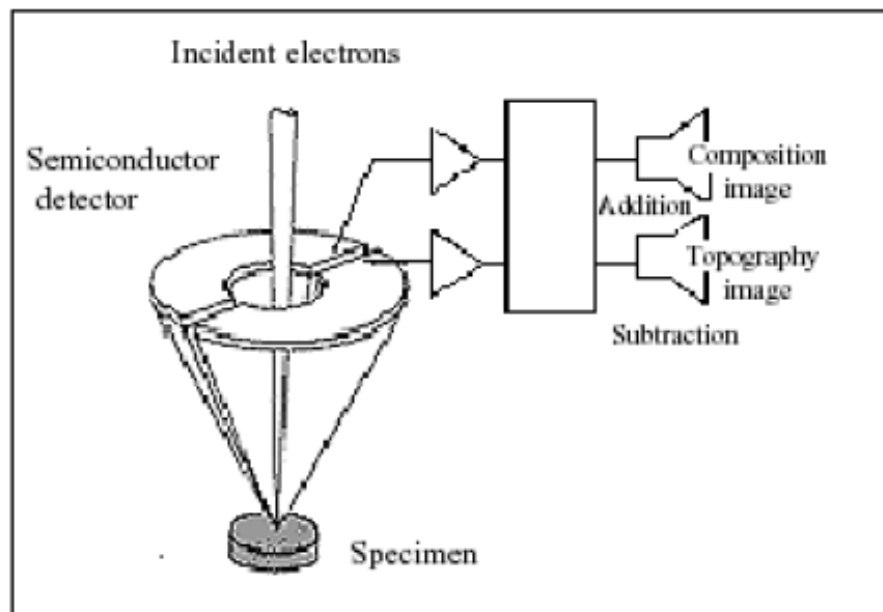


Fig. 18. Backscattered electron detector.

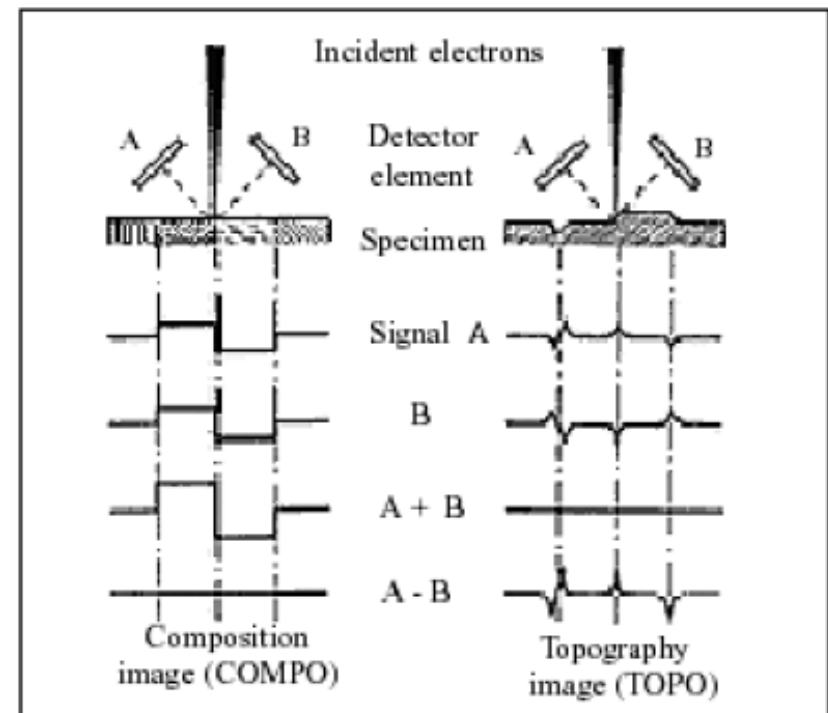
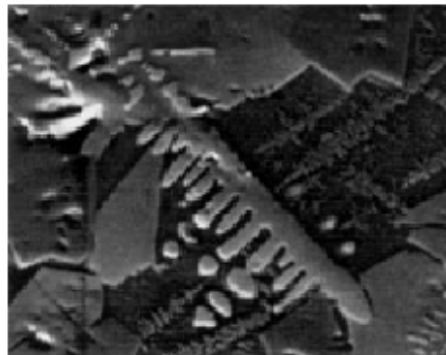


Fig. 19. Principles of composition image and topography image

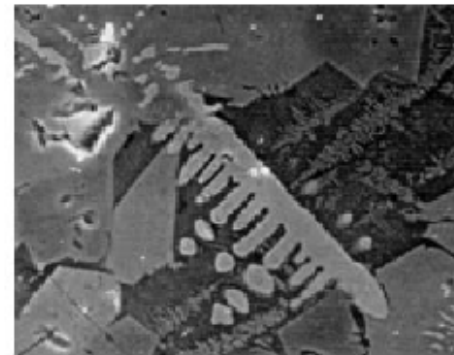
Composition of Signals - Slug 20 kV, $\times 1,100$

BSE



(a) Backscattered electron image (BEI)

SE



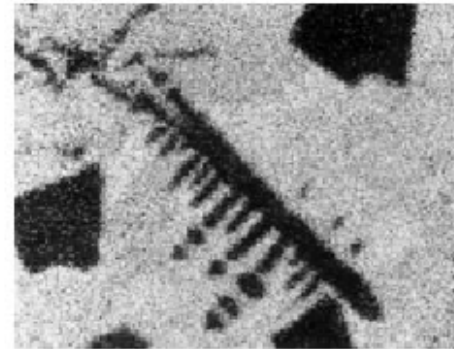
(d) Secondary electron image (SEI)

Topography



(b) Topography image (TOPO)

X-ray (Si)



(e) X-ray image (Si)

Composition



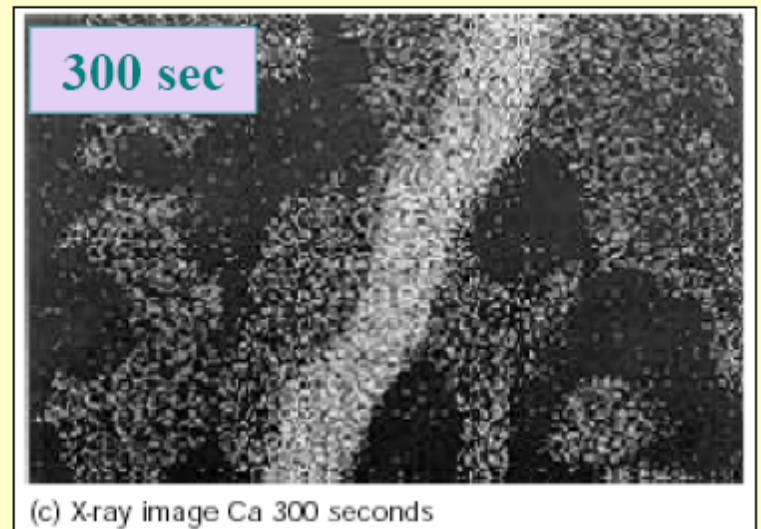
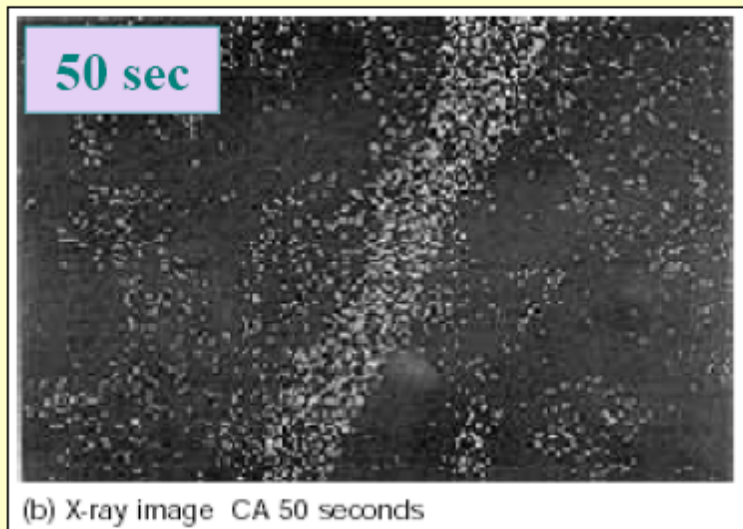
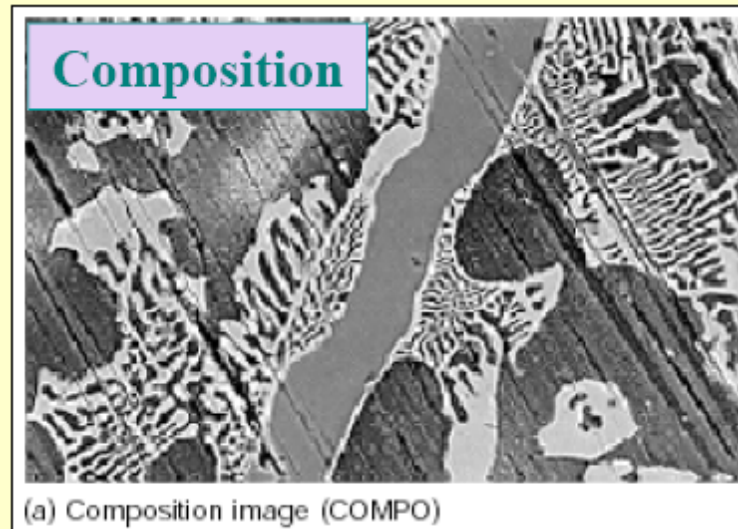
(c) Composition image (COMPO)

**X-ray
(Al)**



(f) X-ray image (Al)

X-ray Exposure and Composition

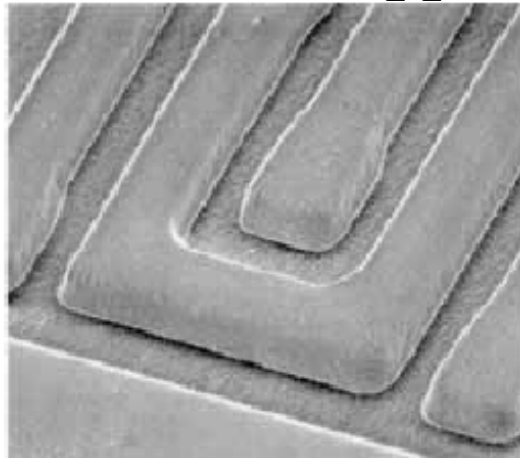


Influence of Charge-Up on Image Quality

Resist

절연도료

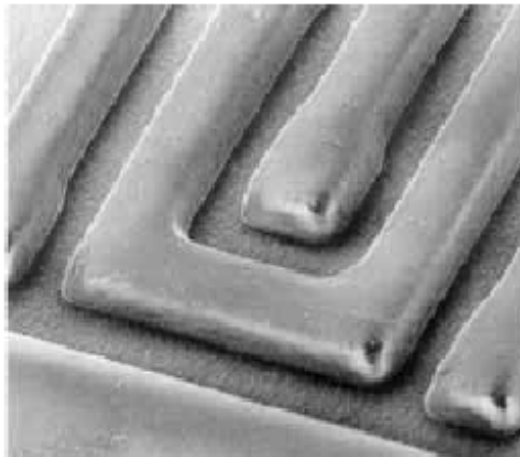
1.0 KV



(a) 1.0 kV

x3,200

1.3 KV



(b) 1.3 kV

x3,200

Vinegar fly

초파리

4 KV



(a) 4 kV

10 KV

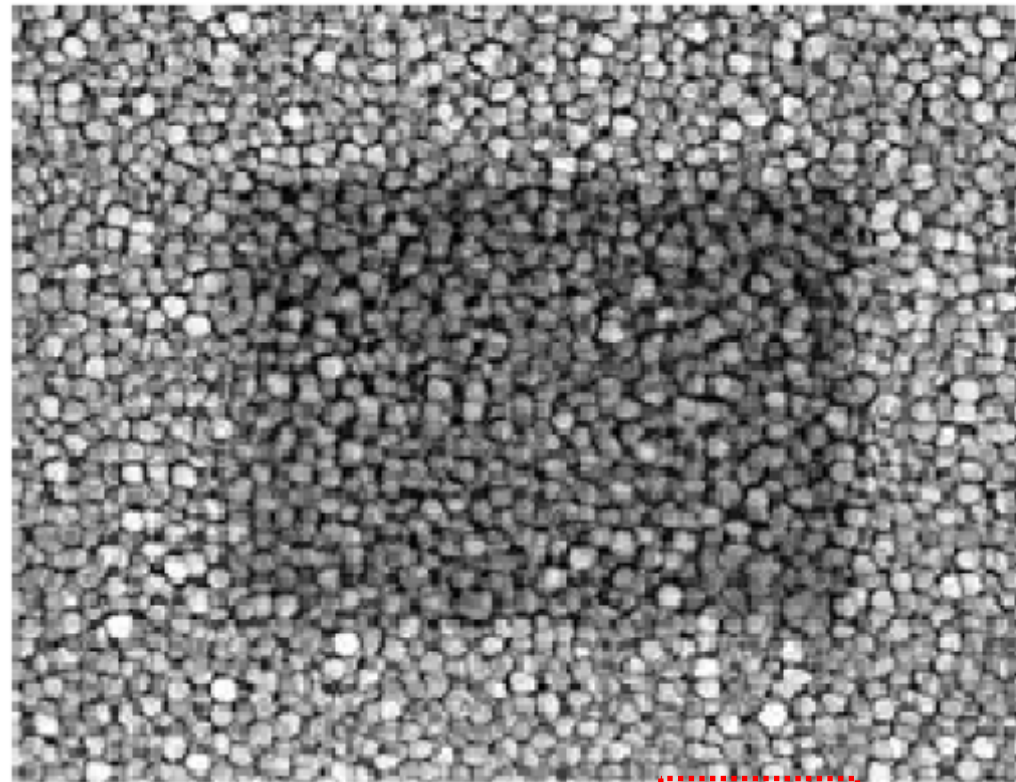


(b) 10 kV

1) Probe current, 2) Accelerating voltage, 3) Tilting angle

Contamination

ITO

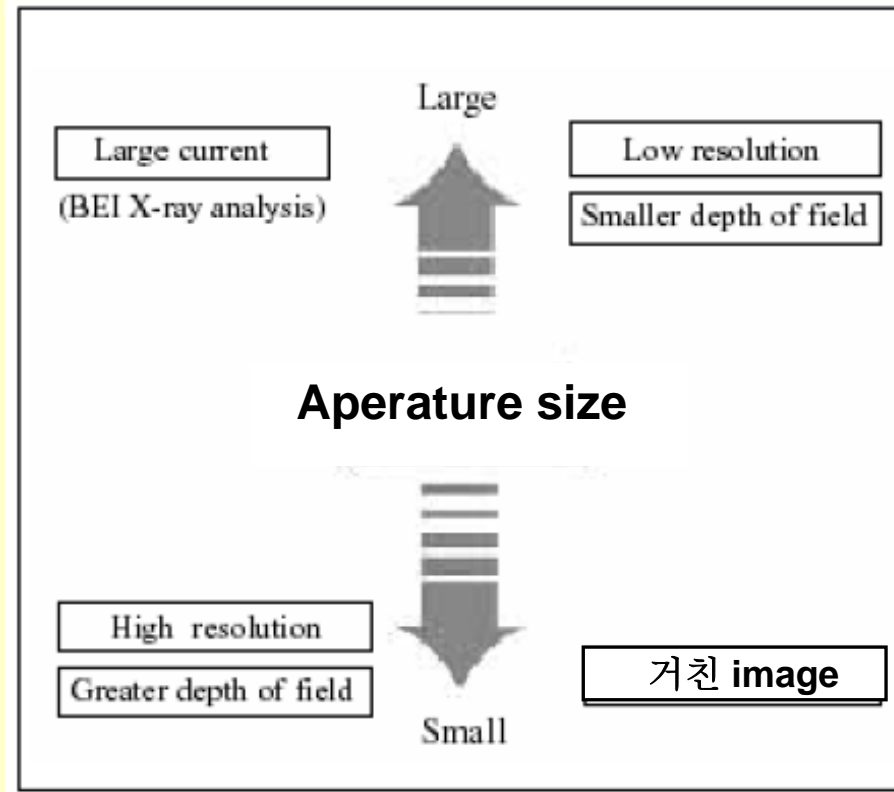
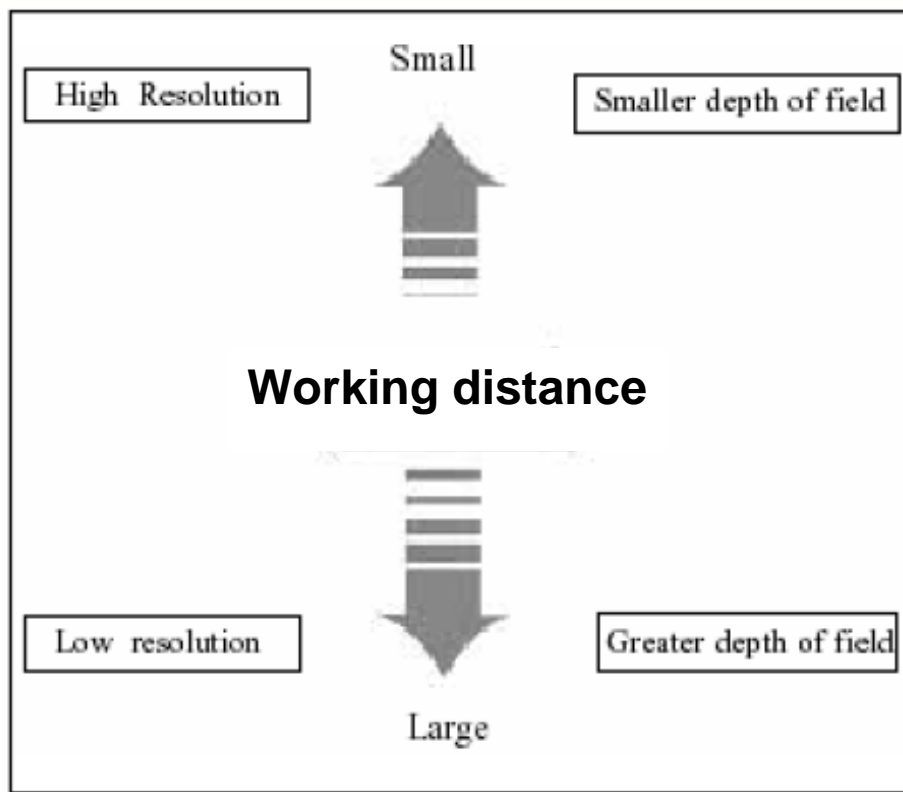


5 kV

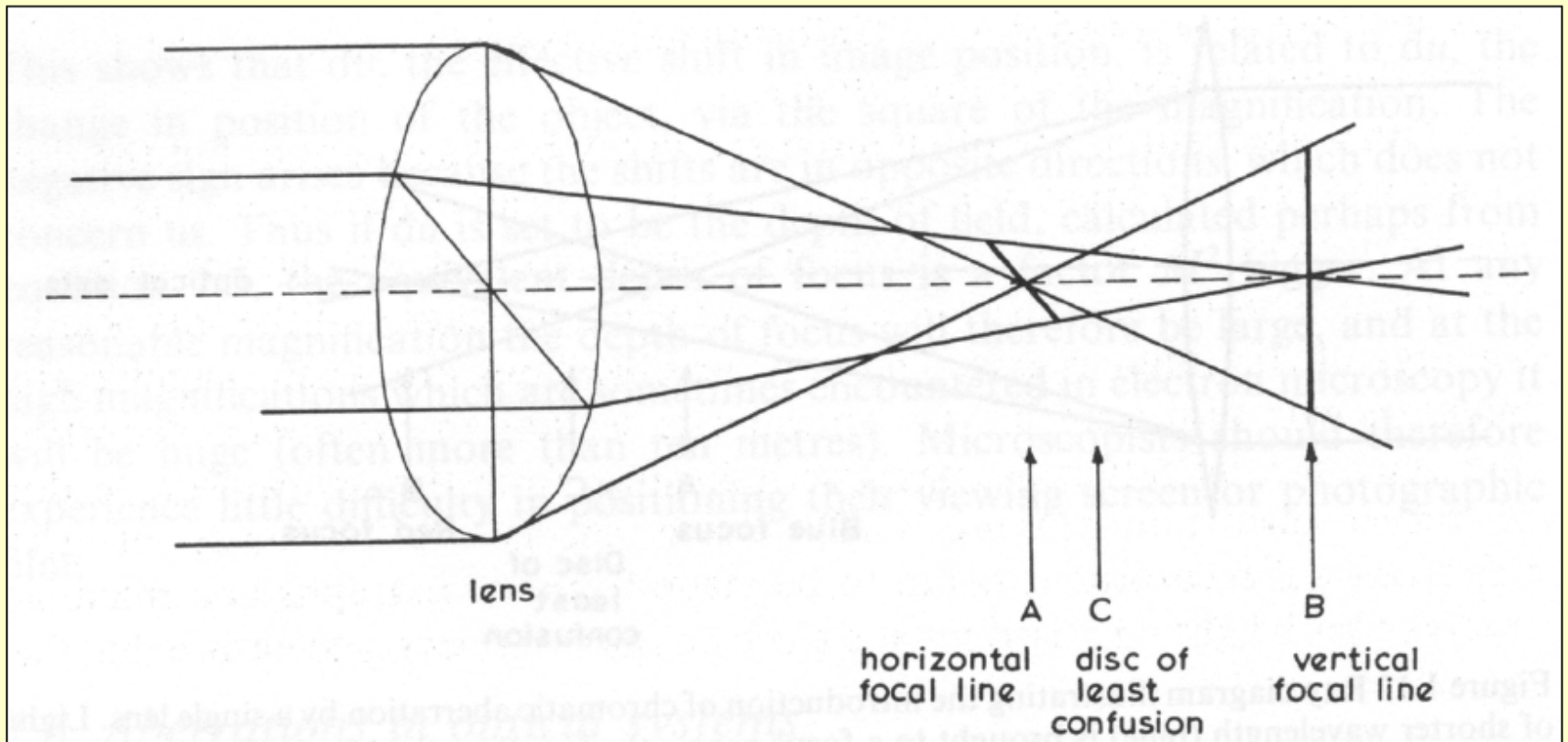
x18,000

1) Dry and clean sample, 2) Low temp, 3) Small samples

Effect of Working Distance and Aperture Size



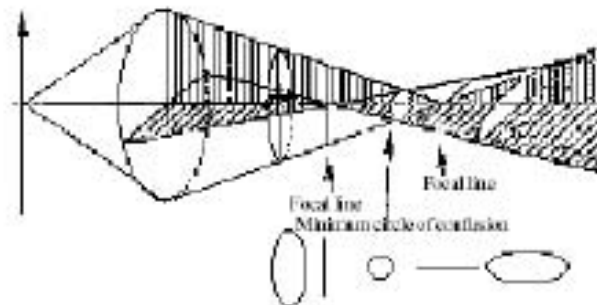
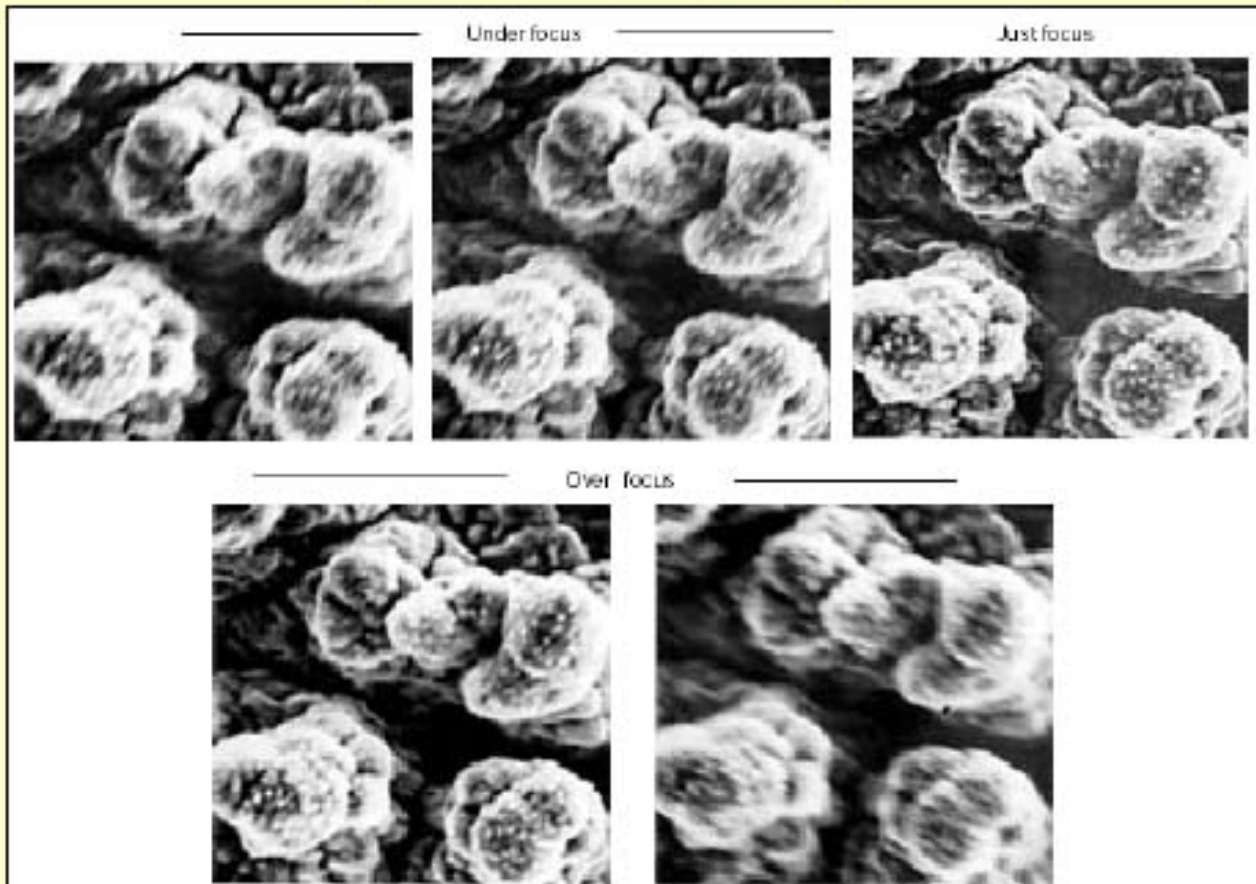
Astigmatism



Formation of **astigmatism** for a lens with slightly different optical properties in the horizontal and vertical directions

Astigmatism

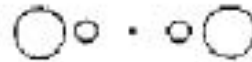
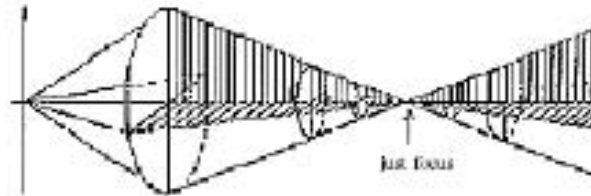
Wrong



(a) Shape changes in electron beam when there is astigmatism

Astigmatism

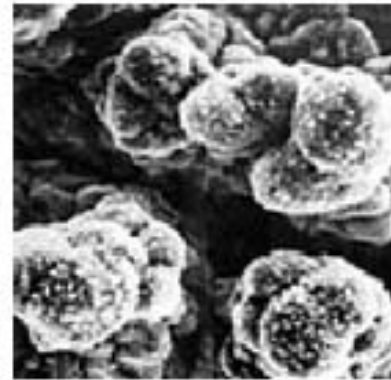
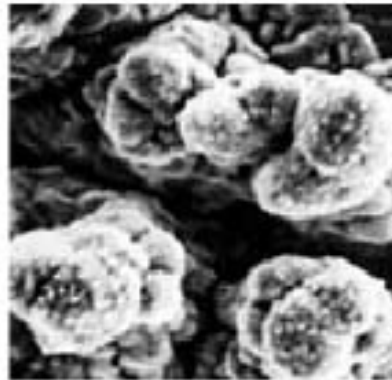
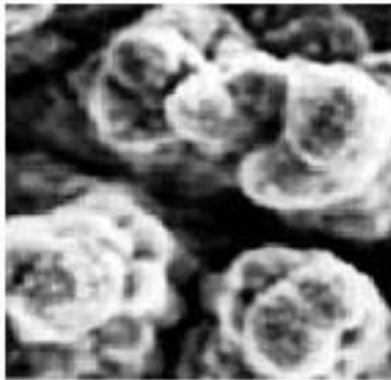
Correct



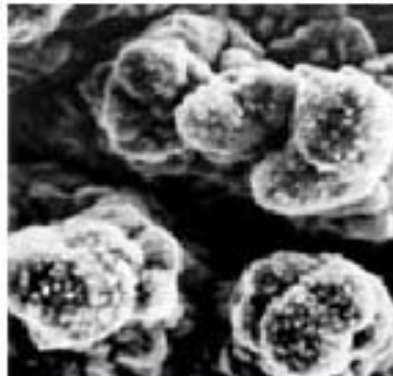
(b) Shape changes in electron beam when astigmatism is corrected

Underfocus

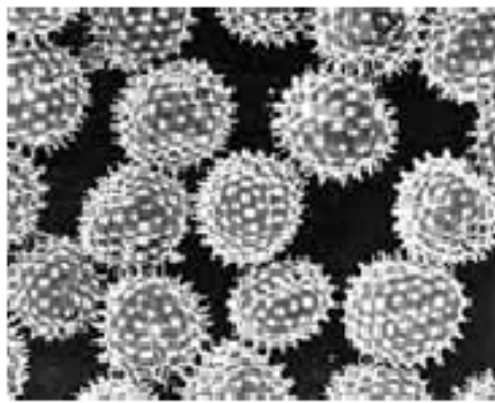
Just focus



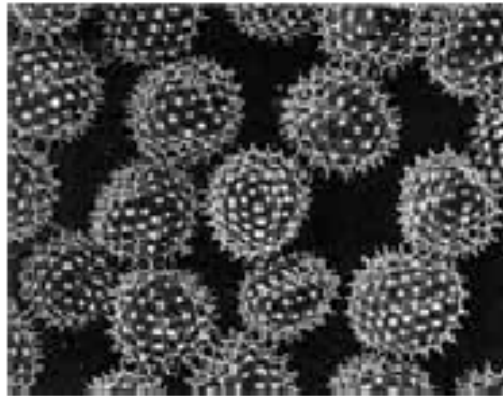
Over focus



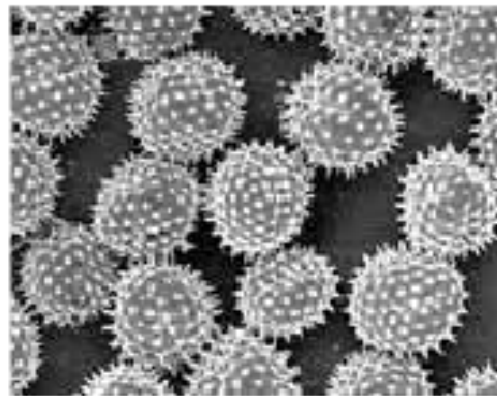
Contrast & Brightness



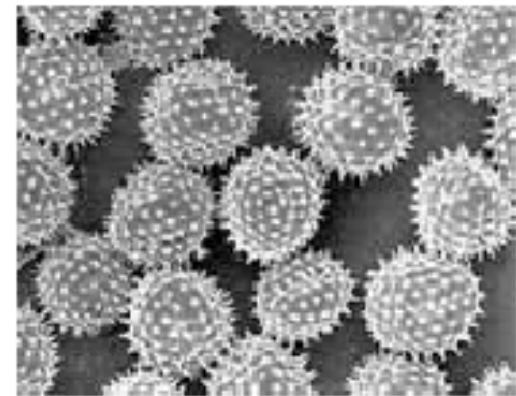
Excessive contrast



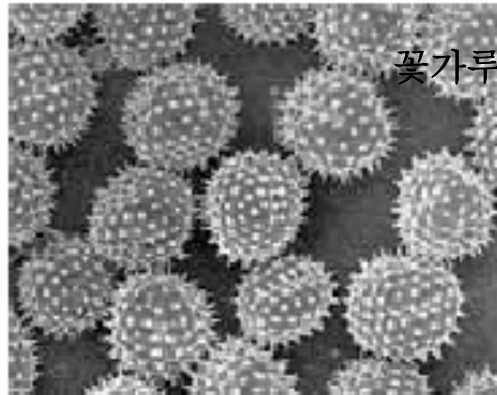
Insufficient brightness



Optimum



Excessive brightness



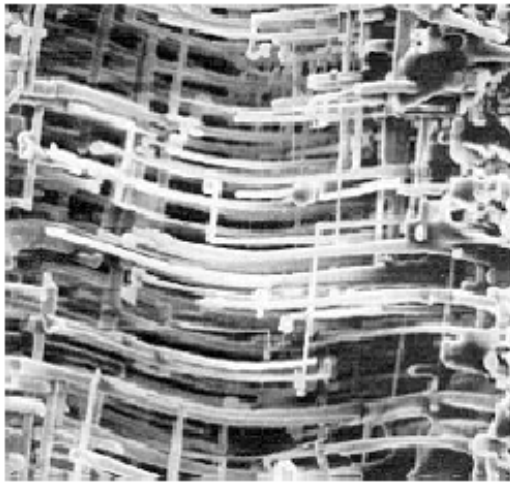
Insufficient contrast

**Pollen of
marigold**

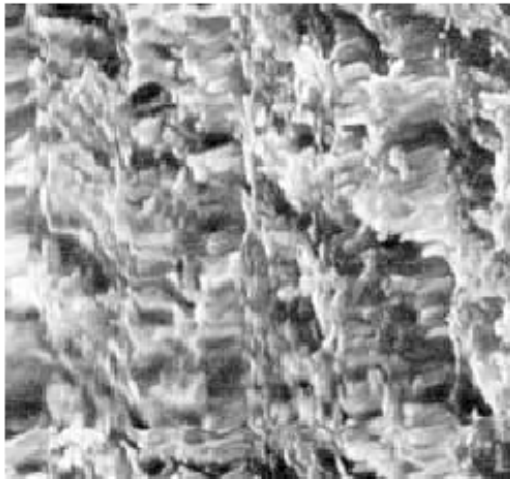
x360

External Disturbances

Magnetic Field



(a) Influenced by external magnetic field.



(b) Influenced by external magnetic field

Influenced

Uninfluenced

Mechanical vibration

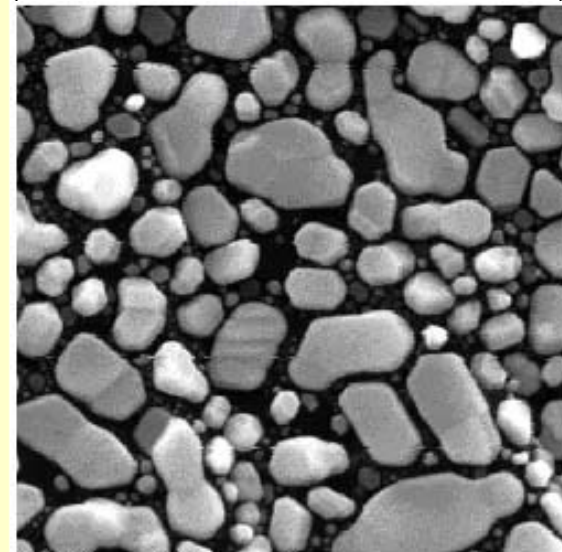
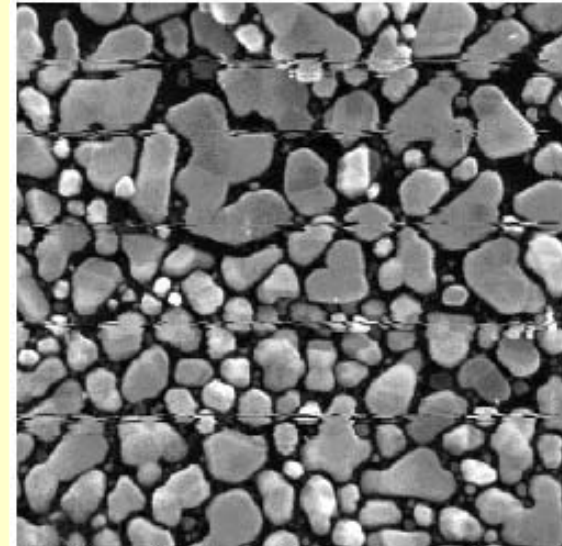
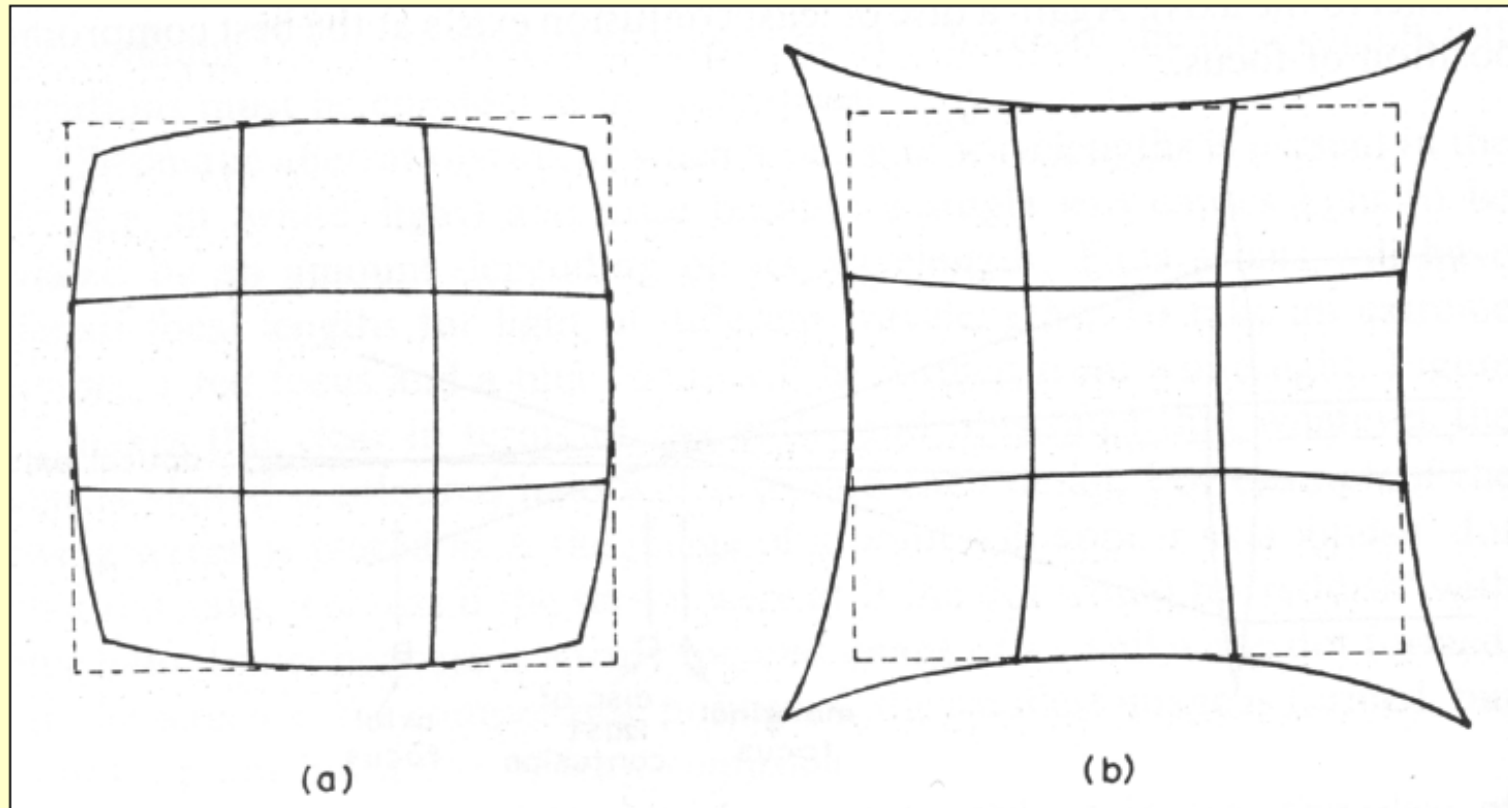


Image Distortion



Barrel

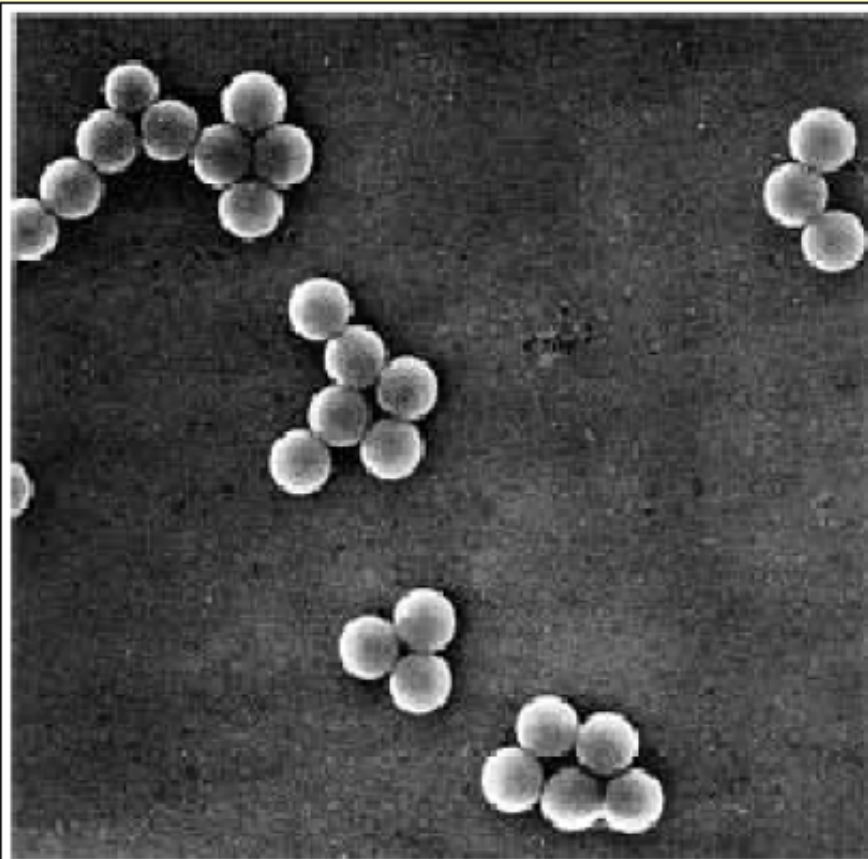
Pin-cushion

Barrel – Magnification **decreases** with distance from optical axis

Pin-cushion – Magnification **increases** with distance from optical axis

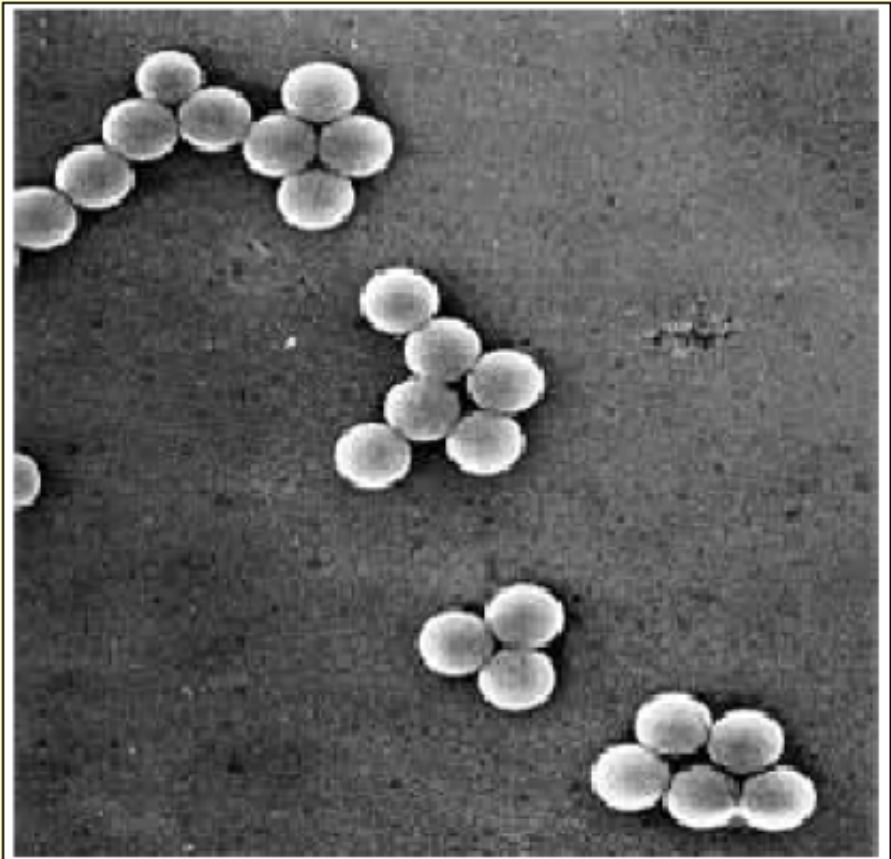
Image Distortion

Normal



(a) Normal Image

Horizontally Distorted



(b) Horizontally distorted image

Latex particles

고무나무 유액

Summary

What you see.....

Is not necessarily what you get!!!

Be careful with images...